

Inventor: Garo J. Derderian  
Title: Deposition Methods  
Assignee: Micron Technology, Inc.  
Docket No. MI22-2373

**INFORMATION DISCLOSURE STATEMENT**

**PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98**


In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation application of co-pending application Serial No. 10/261,735, filed September 30, 2002. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 30 Sep 2003

By:   
James E. Lake  
Reg. No. 44,854

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2373	PRIORITY SERIAL NO. 10/261,735		
<b>LIST OF ART CITED BY APPLICANT</b> (Use several sheets if necessary)				APPLICANT Garro J. Derderian			
				PRIORITY FILING DATE September 30, 2002		PRIORITY GROUP 1762	
<b>U.S. PATENT DOCUMENTS</b>							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,270,247	12/1993	Sakuma et al			
	AB	6,270,572	08/2001	Kim et al			
	AC	6,083,832	07/2000	Sugai			
	AD	4,369,105	01/1983	Caldwell et al			
	AE	4,831,003	05/1989	Lang et al			
	AF	6,287,965	09/2001	Kang et al			
	AG	5,480,818	01/1996	Matsumoto et al			
	AH	6,203,613	03/2001	Gates et al			
	AI	6,174,377	01/2001	Doering et al			
	AJ	5,916,365	06/1999	Sherman			
	AK	6,335,561	03/2000	Sandhu			
	AL						
<b>FOREIGN PATENT DOCUMENTS</b>							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AM	EP 0794568	10/1997	Europe			
	AN	05-251339	09/1993	Japan			
	AO						
	AP						
	AQ						
<b>OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)</b>							
	AR	Kiyoko et al., Patent Abstract Application No. 04-024917 (JP 9224917, 09/1993), "Semiconductor Substrate and Its Manufacture."					
	AS	Ritala, et al., "Atomic Layer Epitaxy - A Valuable Tool for Nanotechnology?" Nanotechnology, Vol. 10, No. 1, pps. 19-24, March 1999.					
	AT	George, et al., "Surface Chemistry for Atomic Layer Growth", Journal of Physical Chemistry, Vol. 100, No. 31, pps. 13121-13131, August 1, 1996.					
	AU	Suntola, "Atomic Layer Epitaxy", Handbook of Crystal Growth, Vol. 3, Chapter 14, pps. 602-663.					
	AV	Vernon, S.M., "Low-cost, high-efficiency solar cells utilizing GaAs-on-Si technology." Dialog Abstract of Report No. NREL/TP-451-5353; 04/1993.					
EXAMINER				DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA	4,913,090	04/1990	Harada et al				
AB	6,307,184	10/2001	Womack et al				
AC	5,616,208	04/1997	Lee				
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AG	5,997,588	12/1999	Goodwin et al				
AH	3,785,853	01/1974	Kirkman et al				
AI	6,139,695	10/2000	Washburn et al				
AJ	6,355,561	03/2002	Sandhu et al				
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR	Suntola, "Surface Chemistry of Materials Deposition at Atomic Layer Level", Applied Surface Science, vol. 100/101, March 1996, pp. 391-398.					
	AS	Aarik et al, "Effect of Growth Conditions on Formation of TiO <sub>2</sub> -II Thin Films in Atomic Layer Deposition Process", Journal of Crystal Growth, Vol. 181, August 1997, pp. 259-264.					
	AT	Skarp, "ALE-Reactor for Large Area Depositions", Applied Surface Science, vol. 112, March 1997, pp. 251-254.					
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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	09/652,533	Sandhu			08/2000
	AB	09/643,004	Mercaldi			08/2000
	AC	09/927,230	Doan			08/2001
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					
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*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	6,479,902	11/2002	Lopatin et al			
	AB	6,458,416	10/2002	Derderian et al			
	AC	6,368,954	04/2002	Lopatin et al			
	AD	6,235,571	05/2001	Doan			
	AE	6,066,358	05/2000	Guo			
	AF	5,366,953	11/1994	Char et al			
	AG	5,273,930	12/1993	Steele et al			
	AH	2002/0125516	09/2002	Marsh et al			
	AI						
	AJ						
	AK						
	AL						
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	AO						
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	AP		Aarik, et al, "Control of Thin Film Structure by Reactant Pressure in Atomic Layer Deposition of TiO <sub>2</sub> ," Journal of Crystal Growth, 169 (1996) pgs. 496-502				
	AQ						
	AR						
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